IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Grimbergen et al.

Group Art Unit: 1792

Serial No: 09/595,778 Confirmation No: 6490 Examiner: Allan W. Olsen

Filing Date: June 16, 2000

Attorney Docket No:

For: APPARATUS AND METHOD FOR

002077 USA D01/ETCH/SILICON/MDD

MONITORING PROCESSING OF A

July 17, 2008

SUBSTRATE

San Francisco, California

DECLARATION PURSUANT TO 37 C.F.R. § 1.131

Box Fee Amendment Commissioner for Patents Washington, D.C. 20231

Examiner Olsen:

- I. This declaration is to establish conception of the invention of this application in the United States, at a date prior to December 17, 1996, which is the effective date of U.S. Patent No. 5,985,092 to Chiu et al., and further to establish diligent work on the invention from a date prior to December 17, 1996 and up until the invention was reduced to practice.
- II. The persons making this declaration are the inventors of the present application.
- III. Attached to this Declaration is: Exhibit A, titled "Sensor Program Update", part of a presentation by the inventors which describes aspects of the present invention. Dates have been removed from the document. The presentation was drafted prior to December 17, 1996.

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IV. From EXHIBIT A it can be seen that the inventors had conceived of a method of processing a substrate in a process chamber comprising a wall, the method comprising: providing a substrate in the process chamber, the substrate having a surface; introducing a gas into the process chamber; energizing the gas by passing RF energy through the wall of the process chamber to the gas inside the process chamber to energize the gas; detecting radiation reflected from the substrate from directly above the surface of the substrate after the radiation propagates through the wall; and evaluating the detected radiation to monitor the depth of a layer being processed on the substrate, as claimed in claim 1.

- V. From Exhibit A it can be further seen that the inventors had conceived of a method of processing a substrate in a process chamber comprising a wall and having a non-vertical multi-turn antenna above the wall, the method comprising: placing in the process chamber, a substrate having a layer; introducing a gas into the process chamber; powering the non-vertical multi-turn antenna to couple energy through the wall to the gas inside the process chamber to energize the gas to process the layer on the substrate; detecting radiation reflected from the substrate and propagating through the wall; and evaluating the detected radiation to monitor the depth of the layer being processed on the substrate, as claimed in claim 105.
- VI. Exhibit A also demonstrates that the inventors had conceived of a method of processing a substrate in a process chamber comprising a ceiling and an antenna above the ceiling, the method comprising: providing a substrate in the process chamber, the substrate having a surface; introducing a gas into the process chamber; energizing the gas by applying an RF current to the antenna to pass RF energy through the ceiling of the process chamber to the gas inside the process chamber to energize the gas; detecting radiation reflected from the substrate from directly above the surface of the substrate after the radiation propagates through the ceiling; and evaluating the detected radiation to monitor processing of the substrate, as claimed in claim 106.

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VII. Exhibit B is a receipt for a UV photo-sensor used to make a prototype apparatus

capable of performing the invention of claims 1, 105 and 106. Date information has

been redacted from the receipt. However, the receipt date is prior to December 17,

1996.

IIX. Exhibit C is a receipt for a UV lamp used to make a prototype apparatus capable

of performing the invention of claims 1, 105 and 106. Date information has been

redacted from the receipt. However, the receipt date is prior to December 17, 1996.

IX. Exhibit D is a receipt for a UV lamp used to make another prototype apparatus

capable of performing the invention of claims 1, 105 and 106. Date information has

been redacted from the receipt. However, the receipt date is prior to December 17,

1996.

X. Exhibit E is a receipt for a set of UV mirrors to fold the optical beam of a

prototype apparatus capable of performing the invention of claims 1, 105 and 106.

Date information has been redacted from the receipt. However, the receipt date is prior

to December 17, 1996.

XI. From Exhibits B, C, D and E it can be seen that diligent work to reduce the

invention of claims 1, 105 and 106 to practice began at a date prior to December 17,

1996.

XII. Exhibit F is an excerpt of a presentation titled "DPS Recess Endpoint Status",

dated January 22, 1997. Inventors had completed a UV source assembly prototype,

and dome with fused window had been successfully mounted on a chamber system.

XIII. From Exhibit F it can be seen that the invention was diligently worked on in the

month of January, 1997.

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XIV. The activity evidenced by exhibits B, C, D, E and F was performed in the order

listed. At no time was the gap between evidenced adjacent steps greater than a span

of two months.

XV. Exhibit G is a photograph showing a working chamber capable of performing the

processes of claims 1, 105 and 106. The photograph of Exhibit G was taken with a

digital camera and has a file creation date of February 20, 1997.

XVI. Exhibit G shows that the invention was reduced to practice at least as early as

February 20, 1997.

XVII. As the person signing below, I hereby declare that all statements made herein of

my own knowledge are true and that all statements made on information and belief are

believed to be true; and further that these statements were made with the knowledge

that willful false statements and the like so made are punishable by fine or

imprisonment, or both, under Section 1001 of Title 18 of the United States Code, and

that such willful false statements may jeopardize the validity of the application or any

patent issued thereon.

First Inventor: Michael Grimbergen

Signature: _

Date:

Residence: 767 Martinique Drive

Redwood City, California 94065

Country of Citizenship: United States of America

Second Inventor: Shaoher X. Pan

Signature:

Date: 7/1.6 / 2008

Residence: 1133 Kelez Drive

San Jose, California 95120

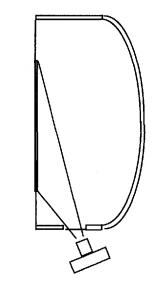
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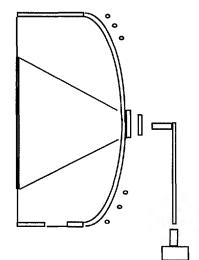
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DPS Implementation Plan

through side window Demonstrated interferometry

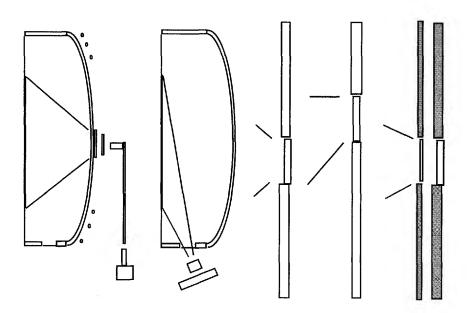
- good image quality
- topography effect
- wafer weaker fringe visibility far side of
- **Top-down DTCU implementation**
- requires window in ceramic dome
- limited room for CCD camera
- image-preserving relay fiber bundle





LES Chamber Integration Options

- MxP Unilid 21+112 hole GDP two windows
- MxP+ Off-center Sapphire Window single window
- MxP+ Center See-thru SGD centered single window
- **DPS** side port glancing angle
- DPS top-down



Recess Etch Endpoint

Chamber Hardware:

- Lid with window (MxP/Mk II)
- Dome under development (DPS)

- **Endpoint Hardware:** Monochromatic UV Illumination through top of chamber
- Optical fiber on top of chamber to std. endpoint system

Endpoint Software:

- ENDP28 Etch-to-depth
- Calculates etch rate and endpoint to desired depth

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DPS Recess Etch Plan

- Fabricate quartz dome with UV FS window fused in center
- Fabricate UV source/fiber detector assembly
- Etch 16 Mb Recess 1 wafer
- use emission for planarization etch
- evaluate signal intensity in HDP
- use modified EP S/W with AGC
- evaluate fringe visibility at 254nm

Etch 256 Mb Recess 2 wafer 1.5 um deep

- Redesign prototype
- Modify S/W for early AGC for Recess 2,3

OEG. 2 1996



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Jelight Company, Inc. 2 Mason, Irvine, CA 92718 PHONE: (714) 380-8774 + FAX: (714) 768-9487

SHIP TO:

MIKE GRIMBERGEN
APPLIED MATERIALS
767 MARTINIQUE DRIVE

REDWOOD CITY, CA 94465-1339

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人名马比西班西古英国英国英国英国英国英国英国英国英国英国英国英国英国英国

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MIKE GRIMBERGEN
APPLIED MATERIALS
767 MARTINIQUE DRIVE
REDWOOD CITY, CA 94065-1339

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MIKE N GRIMBERGEN/CA

(~14) 366-8866

ORDER NUMBER: 0006423

SALESPERSON FRANK SCOTT

DUE DATE

SHIP TO:

MIKE N GRIMBERGEN/CA 767 MARTINIQUE DRIVE

BILL TO: VISA CARD # 3903 EXP 6/99

REDWOOD CITY

SOLD TO:

CA 94065

REDWOOD CITY CA 94065

CONFIRM TO: MICHAEL N GRIMBERGEN

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NOTE: COAT WITH -73 ULTRAVIOLET ALUMINUM

Recess Etch Endpoint for DPS

Status

- UV (254nm) source assembly prototypes completed
- UV Quartz window fused into quartz dome mounted on EP1

Approach

Mount UV source assembly above quatrz dome inside unheated dome unit

Lmited chamber availability

- Demonstrate endpoint hardware feasibility with quartz dome on EP1 chambe
- Assess demonstrated process on A3 chamber with quartz

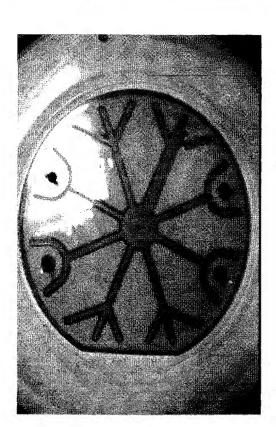
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LES View from Top of Dome







6" e-chuck, EP1 - no DTCU 8mm lens, 610nm wavelength

